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039153-0447 (G1152)SERIAL NO. 10/014439
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INFORMATION DISCLOSURE CITATION

(Use several sheets if necessary)

#2

APPLICANT

Lukanc et al.

FILING DATE

12/11/2001
Unknown

GROUP ART UNIT

Unknown 1756

U.S. PATENT DOCUMENTS

EXAMINER INITIAL	REF	DOCUMENT NUMBER	DATE	NAME	CLASS	SUB- CLASS	FILING DATE IF APPROPRIATE
	A1	09/772,527		Todd Lukanc			01/30/2001
<i>nm</i>	A2	6,228,539 B1	05/08/2001	Wang et al.	430	5	
<i>nm</i>	A3	5,858,580	01/12/1999	Wang et al.	430	5	
<i>nm</i>	A4	5,807,649	09/15/1998	Liebmann et al.	430	5	
<i>nm</i>	A5	5,573,890	11/12/1996	Spence	430	311	

U.S. PTO
10/016439
12/11/01

FOREIGN PATENT DOCUMENTS

	REF	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUB- CLASS	TRANSLATION	
							YES	NO

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

<i>nm</i>	A6	✓	Levenson et al., "Improving Resolution in Photolithography with a Phase-Shifting Mask," IEEE Transactions On Electron Devices, Vol. ED-29, No. 12, December 1982, pp. 1828-36.					
<i>nm</i>	A7	✓	Lin, B.J., "Phase-Shifting Masks Gain an Edge," Circuits & Devices, March 1993, pp. 28-35.					

EXAMINER

W. G. G. G.

DATE CONSIDERED

9/24/03

* EXAMINER: Initial if citation considered, whether or not citation is in compliance with MPEP 609; Draw line through citation if not in compliance and not considered. Include any copy of this form with next

Substitute for form 1449B/PTO

Date Submitted: May 24, 2009

(use as many sheets as necessary)

Sheet	1	of	1
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Complete if Known

Application Number	10/016,439
Filing Date	12/11/2001
First Named Inventor	Todd P. Lukanc
Group Art Unit	1756
Examiner Name	Unknown
Attorney Docket Number	039153-0447 (G1152)

U.S. PATENT DOCUMENTS

[illegible]

FOREIGN PATENT DOCUMENTS

[illegible]

OTHER PRIOR ART - NON PATENT LITERATURE DOCUMENTS

Examiner Initials*	Cite No. ¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.) date, page(s), volume-issue number(s), publisher, city and/or country where published.	T ⁶
	A5/ ✓	Levenson et al., "Improving Resolution in Photolithography with a Phase-Shifting Mask," IEEE Transactions on Electron Devices, Vol. ED-29, No. 12, December 1982, pp. 1828-1836.	
	A6 ✓	Lin, B.-J., "Phase-Shifting Masks Gain an Edge," Circuits & Devices, March 1993, pp. 28-35.	

**Examiner
Signature**

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Considered

9/21/03

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Standard ST. 3. 4. For Japanese patent documents, the indication of the year of the reign of the Emperor must precede the serial number of the patent document.
5. Kind of document by the appropriate symbols as indicated on the document under WIPO Standard ST. 16 if possible. 6. Applicant is to place a check mark here if English language Translation is attached.

Burden Hour Statement: This form is estimated to take 2.0 hours to complete. Time will vary depending upon the needs of the individual case. Any comments on the amount of time you are required to complete this form should be sent to the Chief Information Officer, U.S. Patent and Trademark Office, Washington, D.C. 20231. **DO NOT SEND FEES OR COMPLETED FORMS TO THIS ADDRESS. SEND TO:** Assistant Commissioner for Patents, Washington, D.C. 20231.

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